

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re Patent Application of

Inventors: Michael Weber-Grabau et al.

Application No.: 09/927,102

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For: CRITICAL DIMENSION METROLOGY
SYSTEM INTEGRATED INTO
SEMICONDUCTOR WAFER PROCESS
TOOL

Group Art Unit: 2877

Examiner: R.R. Rosenberger

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I hereby certify that this correspondence is being deposited with the United States Postal Service as First Class Mail in an envelope, addressed to: Commissioner for Patents, P.O. Box 1450 Alexandria, VA 22313-1450 on July 16, 2004.

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